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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/050,499	01/16/2002	Bhanwar Singh	F0653	7713
29393	7590 12/09/2003		EXAMINER	
ESCHWEILER & ASSOCIATES, LLC			VU, DAVID	
NATIONAL CITY BANK BUILDING 629 EUCLID AVE., SUITE 1210 CLEVELAND, OH 44114		G	ART UNIT	PAPER NUMBER
			2818	

DATE MAILED: 12/09/2003

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)				
	10/050,499	SINGH ET AL.				
Office Action Summary	Examin r	Art Unit				
	DAVID VU	2818				
Th MAILING DATE of this communication app	<u> </u>					
Period for Reply						
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.1 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a repl If NO period for reply is specified above, the maximum statutory period to Failure to reply within the set or extended period for reply will, by statute - Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b). Status	36(a). In no event, however, may a reply be to y within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	mely filed ys will be considered timely. the mailing date of this communication. ED (35 U.S.C. § 133).				
1)⊠ Responsive to communication(s) filed on <u>18</u> .	July 2003 .					
2a)☐ This action is FINAL . 2b)⊠ Th	nis action is non-final.					
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213. Disposition of Claims						
4) Claim(s) 1-29 is/are pending in the application.						
4a) Of the above claim(s) 20-29 is/are withdrawn from consideration.						
5) Claim(s) is/are allowed.						
6)⊠ Claim(s) <u>1-19</u> is/are rejected.						
7) Claim(s) is/are objected to.						
8) Claim(s) is/are objected to. 8) Claim(s) are subject to restriction and/or election requirement.						
Application Papers						
9)☐ The specification is objected to by the Examiner.						
10)⊠ The drawing(s) filed on <u>16 January 2002</u> is/are: a)⊠ accepted or b)□ objected to by the Examiner.						
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).						
11) The proposed drawing correction filed on is: a) approved b) disapproved by the Examiner.						
If approved, corrected drawings are required in reply to this Office action.						
12)☐ The oath or declaration is objected to by the Examiner.						
Priority under 35 U.S.C. §§ 119 and 120						
13)☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).						
a) ☐ All b) ☐ Some * c) ☐ None of:						
1. Certified copies of the priority document	ts have been received.					
2. Certified copies of the priority document	ts have been received in Applica	tion No				
3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received.						
14) Acknowledgment is made of a claim for domest	·					
a) The translation of the foreign language pro	• •					
Attachment(s)						
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449) Paper No(s)	5) Notice of Informal	ry (PTO-413) Paper No(s) Patent Application (PTO-152)				

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DETAILED ACTION

Election/Restrictions

1. Applicant's election with traverse of group I (Claims 1-19) on July 18, 2003 is acknowledged. The traversal is on the ground that a search of both the process and system claims would not present a <u>serious</u> burden to the examiner. This is not found persuasive because a prima facie burden is established by showing separate classification of the two inventions. Here, such separate classification has been shown and thus a burden established. Applicant's mere contention to the contrary is insufficient to overcome such a showing. The requirement is still deemed proper and is therefore made FINAL. Claims 20-29 are withdrawn from further consideration pursuant to 37 CFR 1.142(b), as being drawn to a nonelected invention, there being no allowable generic or linking claim. Applicant timely traversed the restriction requirement in paper filed on July 18, 2003.

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claims 1-19 are rejected under 35 U.S.C. 102(b) as being anticipated by Esquibel (US 5,885,402).

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Regarding claims 1-9, Esquibel in related text (Col. 3, lines 35-61; Col. 4, lines 35-55; Col. 6, line 50-Col. 7, line 3 and Col. 7, lines 52-65) discloses a system for depositing films on a semiconductor wafer comprising: a deposition chamber operable to deposit a film on the semiconductor wafer therein according to one or more process conditions; an acoustic microbalance within the deposition chamber; and a controller, wherein the controller is configured to provide feedback control of the one or more process conditions based on data provided at least in part by the acoustic microbalance.

Regarding claims 10-19, Esquibel in related text (Col. 3, lines 35-61; Col. 4, lines 35-55; Col. 6, line 50-Col. 7, line 3 and Col. 7, lines 52-65) discloses system for depositing films on a semiconductor wafer comprising: a deposition chamber operable to deposit a film on the semiconductor wafer therein according to one or more process conditions; an acoustic microbalance having a cantilever within the deposition chamber (Col. 6, lines 54-66); and a controller, wherein the controller is configured to detect an endpoint of a deposition process based on data provided at least in part by the acoustic microbalance, and wherein the controller comprises a computer system component that encodes a model or database that accounts for a difference between an extent of deposition on the cantilever and an extent of deposition on the semiconductor wafer (Col. 7, lines 52-65 and Fig. 5).

Conclusion

3. Any inquiry concerning this communication or earlier communications from the examiner should be directed to David Vu whose telephone number is (703) 305-0391. The new

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phone number after January 08, 2004 will be (571) 272-1798. The examiner can normally be reached on Monday-Friday from 8:00am to 5:00pm.

If attempt to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Nelms., can be reached on (703) 308-4910. The new phone number after January 08, 2004 will be (571) 272-1787.

DV

David Vu.

Supervisory Patent Examiner

Technology Center 2800